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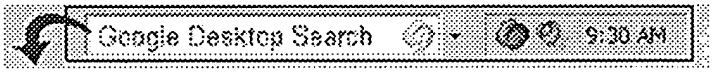
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1 Object oriented simulation tools necessary for a flexible batch process management architecture

Chell A. Roberts, Terrence G. Beaumariage, Yasser Dessouky, Michael K. Ogle

December 1991 **Proceedings of the 23rd conference on Winter simulation**

Publisher: IEEE Computer Society

Full text available: pdf(927.59 KB) Additional Information: full citation, references, index terms

2 Semiconductor manufacturing: Process equipment modeling: resident-entity based simulation of batch chamber tools in 300mm semiconductor manufacturing

Nirmal Govind, David Fronckowiak

December 2003 **Proceedings of the 35th conference on Winter simulation: driving innovation**

Publisher: Winter Simulation Conference

Full text available: pdf(409.51 KB) Additional Information: full citation, abstract, references, citings

This paper describes a resident-entity based pilot simulation study of a class of tools used in 300mm semiconductor manufacturing known as the wets tools or the wet benches. These are batch chamber tools - they have several chambers or tanks, each of which can accommodate a batch of wafers, usually more than one lot size. We develop a simulation model for the wets processing area that is based on the resident-entity paradigm, but makes use of trans ...

3 Semiconductor manufacturing: Understanding the impact of equipment and process changes with a heterogeneous semiconductor manufacturing simulation environment

Jeffrey W. Herrmann, Brian F. Conaghan, Laurent Henn-Lecordier, Praveen Mellacheruvu, Manh-Quan Nguyen, Gary W. Rubloff, Rock Z. Shi

December 2000 **Proceedings of the 32nd conference on Winter simulation**

Publisher: Society for Computer Simulation International

Full text available: pdf(1.01 MB) Additional Information: full citation, abstract, references

Simulation models are useful to predict and understand the impact of changes to a manufacturing system. Typical factory simulation models include the parts being manufactured in the factory and the people and resources processing and handling the parts. However, these models do not include equipment or process details, which can affect operational performance such as cycle time and inventory. Separate models are

. used to evaluate processes and equipment. Thus, it is difficult to evaluate the oper ...

4 Semiconductor manufacturing: Process equipment modeling: making optimal design decisions for next generation dispensing tools

Brian P. Prescott, Todd LeBaron

December 2003 **Proceedings of the 35th conference on Winter simulation: driving innovation**

Publisher: Winter Simulation Conference

Full text available: pdf(411.45 KB) Additional Information: full citation, abstract, references

The competitive environment faced by semiconductor equipment suppliers leaves no room for error when designing next generation tools. In addition, time to market, footprint, and equipment capabilities are all key to a successful product. At Cookson Electronics Equipment, tool designers used simulation to answer some difficult design questions, improve time to market, and lower development costs. This paper explains how simulation was used in designing the new High Volume Batch (HVB) dispensin ...

5 A simulation-based decision support system for a specialty chemicals production plant

George S. Bernstein, Eric C. Carlson, Richard M. Felder, Roger E. Bokeny

December 1992 **Proceedings of the 24th conference on Winter simulation**

Publisher: ACM Press

Full text available: pdf(704.07 KB) Additional Information: full citation, references, index terms

6 A combined simulation/optimization approach to process plant design

J. F. Faccenda, R. F. Tenga

December 1992 **Proceedings of the 24th conference on Winter simulation**

Publisher: ACM Press

Full text available: pdf(590.01 KB) Additional Information: full citation, references, citings, index terms

7 Process simulation: successes and failures

Ronald C. Morris

December 1992 **Proceedings of the 24th conference on Winter simulation**

Publisher: ACM Press

Full text available: pdf(691.55 KB) Additional Information: full citation, references, index terms

8 Interactive analysis of simulation output by the method of batch means

Thomas J. Schriber, Richard W. Andrews

December 1979 **Proceedings of the 11th conference on Winter simulation - Volume 2**

Publisher: IEEE Press

Full text available: pdf(1.15 MB) Additional Information: full citation, abstract, references, citings, index terms

An interactive FORTRAN subroutine is presented for use with ongoing simulations to determine and collect the sample size needed to estimate the mean of a process with a specified level of statistical precision. The subroutine can be used with simulation models written in a variety of languages, e.g., FORTRAN, GASP, GPSS, SIMSCRIPT. The subroutine partitions a sequence of observations on the random variable of interest into a series of consecutive batches, finding those batch sizes whose bat ...

9. A simulation approach to capacity expansion for the pistachio hulling process
Yasser Dessouky, Gregg Maggioli, Dave Szeflin
December 1994 **Proceedings of the 26th conference on Winter simulation**
Publisher: Society for Computer Simulation International
Full text available: pdf(665.81 KB) Additional Information: full citation, references, index terms

Keywords: capacity planning, discrete event-network simulation, manufacturing simulation application, pistachio processing

10 Simulated demand in large-scale batch processing acquisitions: role and justification
Ross T. Newkirk, James K. Mullin
October 1974 **ACM SIGSIM Simulation Digest**, Volume 6 Issue 1
Publisher: ACM Press
Full text available: pdf(599.04 KB) Additional Information: full citation, abstract, references

The authors present this paper in the context of a successful acquisition of a multi user large scale batch processing system. They discuss the role of simulated demand (a) in determining basic system requirements, (b) as the major part of system specifications made available to vendors and (c) as a major tool in system testing and evaluation.They discuss the simulation of demand profiles from statistical records and user interviews and how this led to specifying minimum system requirements. The ...

11 Semiconductor manufacturing: Process equipment modeling: application of cluster tool modeling to a 300 mm fab simulation
Sameer T. Shikalgar, David Fronckowiak, Edward A. MacNair
December 2003 **Proceedings of the 35th conference on Winter simulation: driving innovation**
Publisher: Winter Simulation Conference
Full text available: pdf(251.58 KB) Additional Information: full citation, abstract, references

300 mm semiconductor wafer fabrication facilities, like conventional semiconductor fabs, contain many different types of tools. In this paper we discuss a realistic way of representing cluster tools in a simulation model of the entire line. A more realistic representation of cluster tools results in greater accuracy in the output of the simulation model.

12 Validating simulation model cycle times at Seagate Technology
Navdeep S. Grewal, Alvin C. Bruska, Timbur M. Wulf, Jennifer K. Robinson
December 1999 **Proceedings of the 31st conference on Winter simulation: Simulation--a bridge to the future - Volume 1**
Publisher: ACM Press
Full text available: pdf(87.34 KB) Additional Information: full citation, references, index terms

13 A continuous process simulation using GPSS
Robert Greer Lavery
January 1981 **Proceedings of the 13th conference on Winter simulation - Volume 1**
Publisher: IEEE Press
Full text available: pdf(284.86 KB) Additional Information: full citation, abstract, citings, index terms

This paper describes the methodology and results of a simulation of an oil purification process used by a food processing company in Toronto, Ontario. The process involves reacting a mixture of edible oils with a caustic solution to precipitate out various free fatty acid and gum components in the oils in the form of soap solids. The process is discrete in that batches of crude oil are processed individually but the processing of each batch is done on a continuous basis.

14 Semiconductor manufacturing: Modeling methodology: simulation based cause and effect analysis of cycle time and WIP in semiconductor wafer fabrication

Chao Qi, Tuck Keat Tang, Appa Lyer Sivakumar

December 2002 **Proceedings of the 34th conference on Winter simulation: exploring new frontiers**

Publisher: Winter Simulation Conference

Full text available: pdf(342.01 KB) Additional Information: full citation, abstract, references

Semiconductor wafer fabrication is perhaps one of the most complex manufacturing processes found today. In this paper, we construct a simulation model of part of a wafer fab using ProModel® software and analyze the effect of different input variables on selected parameters, such as cycle time, WIP level and equipment utilization rates. These input variables include arrival distribution, batch size, downtime pattern and lot release control. SEMATECH DATASET which has the original actual wa ...

15 Semiconductor manufacturing: Factory scheduling and dispatching: simulation-based assessment of batching heuristics in semiconductor manufacturing

Lars Mönch, Ilka Habenicht

December 2003 **Proceedings of the 35th conference on Winter simulation: driving innovation**

Publisher: Winter Simulation Conference

Full text available: pdf(383.58 KB) Additional Information: full citation, abstract, references

In this paper, we investigate the performance of different dispatching and scheduling heuristics for batching tools in a semiconductor wafer fabrication facility (wafer fab) by means of discrete event simulation. Because the processing times of lots on batching tools are quite large compared to those of other processes, careful batching decisions may have a great impact on the performance of the entire wafer fab. In a first step, we investigate the performance of certain modifications of the ...

16 A simulation model for production scheduling of a facility in a process industry

Todd A. Barnes, L. Leslie Gardner

December 1990 **Proceedings of the 22nd conference on Winter simulation**

Publisher: IEEE Press

Full text available: pdf(473.10 KB) Additional Information: full citation, references, index terms

17 Business process simulation

Kerim Tumay

December 1995 **Proceedings of the 27th conference on Winter simulation**

Publisher: ACM Press

Full text available: pdf(578.74 KB) Additional Information: full citation, references, citings, index terms

18 Simulating semiconductor manufacturing systems: successes, failures, and deep questions

Karl G. Kempf
November 1996 **Proceedings of the 28th conference on Winter simulation**
Publisher: ACM Press
Full text available: pdf(1.06 MB) Additional Information: full citation, references, citings

19 Job and jobstream modeling in the TRW timeshare system simulation
Hans Kaspar, Donald S. Miller
June 1974 **Proceedings of the 2nd symposium on Simulation of computer systems**
Publisher: IEEE Press
Full text available: pdf(1.43 MB) Additional Information: full citation, abstract, references, citings, index terms

The method of modeling user jobs and jobstream utilized in the simulation of the TRW Timeshare System (TRW/TSS) is presented. The paper begins with a brief description of the TRW/TSS. Simulation objectives are given. An overview of the simulator is presented. The actual TRW/TSS user jobstream is given in detail. This is followed by two methods of modeling this user profile; namely, a statistical and a job-trace modeling approach which forms the central discussion of this paper. Sections on ...

20 Business process simulation
Kerim Tumay
November 1996 **Proceedings of the 28th conference on Winter simulation**
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